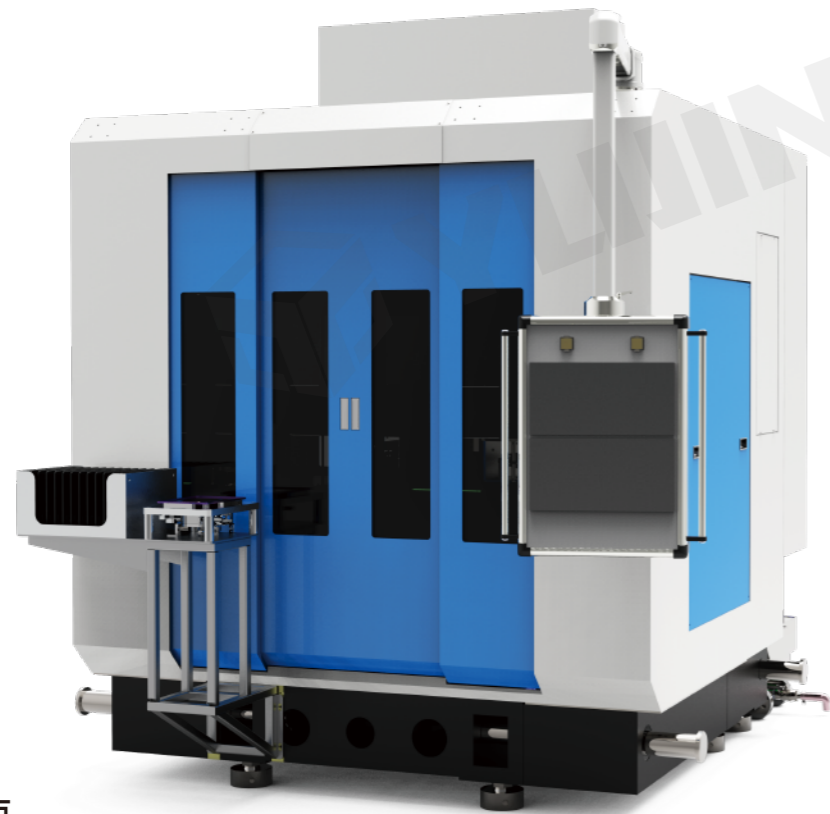


CNC POLISHING MACHINE

数控抛光机SKP1104A

专为4~11英寸异形材料抛光开发

It is specially developed for polishing 4~11 inch special-shaped materia.



设备特点

EQUIPMENT FEATURES

- 双向力控，具备大容量刀库、自动换刀；
- 超强5S防护，为设备实现自动化生产提供必要环境；
- 支持自动化产线二次开发（AGV、地轨、天车）。
- Two-way force control, with large capacity tool magazine, automatic tool change;
- Super 5S protection provides the necessary environment for equipment to achieve automatic production;
- Support the secondary development of automated production lines (AGV, ground rail, overhead crane).

案例展示

EQUIPMENT FEATURES



异形抛光
NON-STANDARD POLISHING

手机/ IWATCH前后盖
SMARTPHONE AND APPLE
WATCH FRONT AND BACK COVERS

IPAD后盖、中框
IPAD BACK COVER
AND MIDDLE FRAME

技术参数

TECHNICAL SPECIFICATIONS

| 项目/ITEMS | 规格/SPECIFICATION |
|--|---|
| 加工尺寸范围 Processing size range | 4-11寸（对角线） |
| 治具最大尺寸 Maximum size of fixture | 250×180（依平台中心安装方式） |
| 刀柄规格 Knife handle specifications | Φ2-Φ16mm（ISO25-ER16夹套） |
| 刀头范围 Blade range | Φ80 以内 |
| 刀具装夹方式 Tool collision clamping method | 气动装夹（不锈钢材质） |
| 平台中心距 Platform center to center distance | 300 mm |
| 设备工作原理 Equipment working principle | 四轴多头高速抛光 |
| C轴旋转角度 C-axis rotation angle | 360度 |
| C轴定位精度/C轴重复定位精度 C-axis repeated positioning accuracy/ C-axis positioning accuracy | 1arcmin / 1arcmin |
| C轴径向跳动精度/C轴平面度1-4# C-axis radial runout accuracy/ C-axis flatness 1-4 | ≤0.02mm / ≤0.05mm |
| X/Y/Z轴行程/X/Y/Z axis travel | 300/550/300mm |
| X/Y/Z轴定位精度 / X/Y/Z轴重复定位精度 X/Y/Z-axis positioning accuracy X/Y/Z axis repeated positioning accuracy | ≤0.015mm / ≤0.01mm |
| 主轴额定转速 Rated spindle speed | 7500rpm（Max 10000rpm） |
| 加工节拍（单周期） Processing rhythm (single cycle) | 根据被加工件要求及尺寸实抛 According to the requirements and size of the processed parts, the actual polishing |